

Resource Summary Report

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Oxford: PlasmaPro 100 Estrelas Plasma Technology

RRID:SCR_020373

Type: Tool

Proper Citation

Oxford: PlasmaPro 100 Estrelas Plasma Technology (RRID:SCR_020373)

Resource Information

URL: <https://plasma.oxinst.com/products/dsie/plasmapro-100-estrelas>

Proper Citation: Oxford: PlasmaPro 100 Estrelas Plasma Technology (RRID:SCR_020373)

Description: Platform is designed to give total flexibility for Deep Silicon Etch applications. Serves diverse set of process requirements across Micro Electro Mechanical Systems and Advanced Packaging and Nanotechnology markets.

Resource Type: instrument resource

Keywords: Oxford, Plasma Technology, Instrument, Resource equipment, Equipment, USEDit,

Availability: Commercially available

Resource Name: Oxford: PlasmaPro 100 Estrelas Plasma Technology

Resource ID: SCR_020373

Alternate IDs: Model_Number_100_Estrelas

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260801T190649+0000

Ratings and Alerts

No rating or validation information has been found for Oxford: PlasmaPro 100 Estrelas Plasma Technology.

No alerts have been found for Oxford: PlasmaPro 100 Estrelas Plasma Technology.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.